CLAIMS

1. A resin composition for stereolithography, which is an actinic radiation-curable resin composition comprising:

a cationic-polymerizable organic compound;

a radical-polymerizable organic compound;

a photo initiator for cationic polymerization; and

a photo initiator for radical polymerization,

wherein the photo initiator for cationic polymerization comprises a compound represented by the following formula (I), the compound having a purity of 80% or higher:

wherein M represents an antimony atom or a phosphorus atom; and the broken line between S⁺ and MF₆ represents an ionic bond.

- 2. The resin composition for stereolithography as claimed in claim 1, wherein the purity of the compound represented by the formula (I) is 90% or higher.
- 3. The resin composition for stereolithography as claimed in claim 1 or 2, wherein the purity of the compound represented by the formula (I) is 95% or higher.
- 4. The resin composition for stereolithography as claimed in any of claims 1 to 3, wherein M in the compound represented by the formula (I) is an antimony atom.
- 5. The resin composition for stereolithography as claimed in any of claims 1 to 4, wherein the cationic-polymerizable organic compound comprises at least one compound

having an epoxy group.

- 6. The resin composition for stereolithography as claimed in any of claims 1 to 5, wherein the radical-polymerizable organic compound comprises at least one compound having a (meth)acryl group.
- 7. The resin composition for stereolithography as claimed in any of claims 1 to 6, which comprises an oxetane compound at a ratio of from 1 to 30% by mass with respect to the mass of the cationic-polymerizable organic compound.
- 8. The resin composition for stereolithography as claimed in any of claims 1 to 7, which comprises a polyalkylene ether compound at a ratio of from 1 to 30% by mass with respect to the mass of the cationic-polymerizable organic compound.